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About the Cover: *The figures are from the paper "Laser microfabrication of L605 cobalt-chromium cardiovascular stent implants with modulated pulsed Nd:YAG laser," by S. Sudheer et al.*

EDITORIAL

- 030101 **Implementing JM<sup>3</sup> Acronyms**  
Burn J. Lin

JM3 LETTERS

- 030501 **Fabrication of implantable microshunt using a novel channel sealing technique**  
Alioune Diouf, Gregory Reimann, and Thomas Bifano

ARTICLES

- 033001 **Impact of finite laser bandwidth on the critical dimension of L/S structures**  
Peter De Bisschop, Ivan Lalovic, and Fedor Trintchouk

- 033002 **Improved model for liquid loss at a dynamic contact line including behaviors of high-index fluids**  
Paul M. Harder and Timothy A. Shedd

- 033003 **Dielectric-thickness dependence of damage induced by electron-beam irradiation on metal nitride oxide semiconductor gate pattern**  
Miyako Matsui, Toshiyuki Mine, Kazuyuki Hozawa, Kikuo Watanabe, Jiro Inoue, and Hiroshi Nagaishi

- 033004 **Temperature dependence of Mo-Au Gibbsian segregating alloys**  
Huatan Qiu, S. N. Srivastava, Keith C. Thompson, Martin J. Neumann, and David N. Ruzic

- 033005 **Role of surfactants in adhesion reduction for step and flash imprint lithography**  
Michael W. Lin, Daniel J. Hellebusch, Kai Wu, Eui Kyoon Kim, Kuan H. Lu, Kenneth M. Liechti, John G. Ekerdt, Paul S. Ho, and C. Grant Willson

- 033006 **Fabrication of quartz mold with submicrometer features based on laser-assisted contact transfer method**  
Yung-Chun Lee, Chun-Hsiang Chen, Cheng-Yu Chiu, and Fuh-Yu Chang

- 033007 **Lineshape and morphology study of structures formed using a reconfigurable photomasking element**  
Anna E. Fox and Adam K. Fontecchio

- 033008 **Novolak resins and the microelectronic revolution**  
Stanley F. Wanat, Robert R. Plass, and M. Dalil Rahman

- 033009 **High-resolution permanent photoresist laminate for microsystem applications**  
Uwe Stöhr, Paul Vulto, Paul Hoppe, Gerald Urban, and Holger Reinecke
- 033010 **Optical properties of Teflon® AF amorphous fluoropolymers**  
Min K. Yang, Roger H. French, and Edward W. Tokarsky
- 033011 **Novel two-dimensional micromachined accelerometer based on thermocapillary heat transfer**  
Ke-Min Liao and Rongshun Chen
- 033012 **Laser microfabrication of L605 cobalt-chromium cardiovascular stent implants with modulated pulsed Nd:YAG laser**  
S. K. Sudheer, Devesh Kothwala, S. Prathibha, Chhaya Engineer, Ankur Raval, and Haresh Kotadia
- 033013 **New approach of fabrication and dispensing of micromachined cesium vapor cell**  
Lukasz Nieradko, Christophe Gorecki, Adel Douahi, Vincent Giordano, Jean Charles Beugnot, Jan Dziuban, and Marco Moraja
- 033014 **Deep lateral anhydrous HF/methanol etching for MEMS release processes**  
Meltem Erdamar, Karthikeyan Shanmugasundaram, Paul Roman, Paul Mumbauer, Maria Klimkiewicz, and Jerzy Ruzyllo
- 033015 **Modeling of electrochemical micromachining: comparison to experiments**  
Deepak Marla, Suhas S. Joshi, and Sushanta K. Mitra
- 033016 **Novel InP-based optical MEMS device**  
Cho Jui Tay, Ramam Akkipeddi, and Mahadevaiah Gopal
- 033017 **Visual-servoing of a six-degree-of-freedom robotic manipulator for automated microassembly task execution**  
Yasser H. Anis, James K. Mills, and William L. Cleghorn

## COMMUNICATIONS

- 039701 **Self-organized and high-density filamentous nanodomain patterns fabricated in lithium niobate by discharge poling**  
Simonetta Grilli, Melania Paturzo, Paolo De Natale, and Pietro Ferraro